

## References

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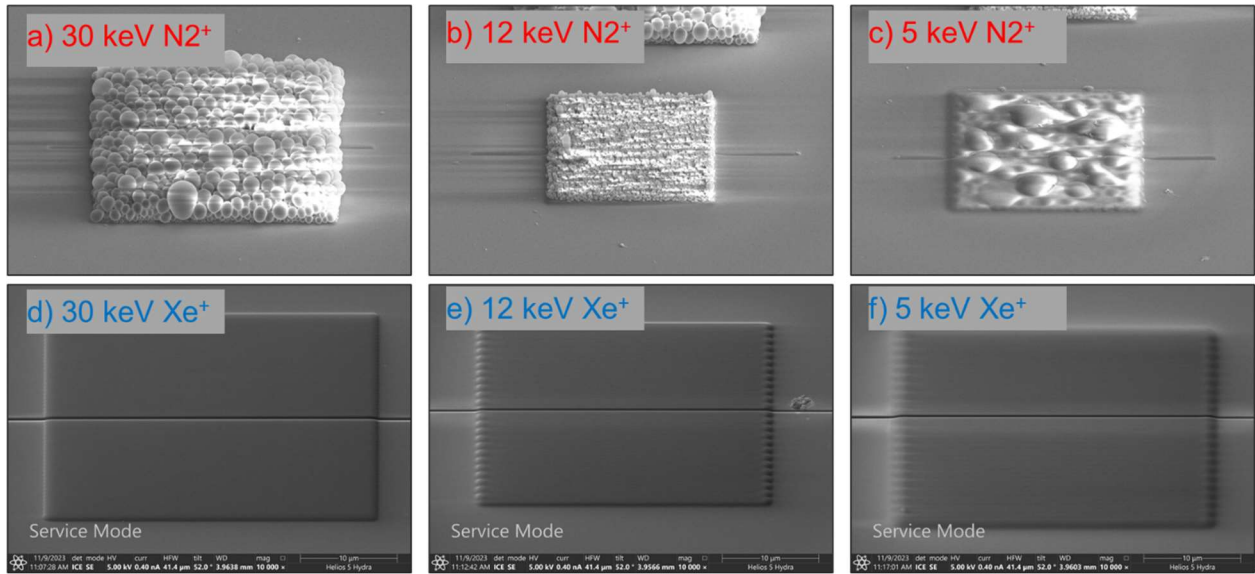


Figure 1. Examples of IDEP 2 (silicate-based insulator) deposited using nitrogen ions (top row, panels a-c) and xenon ions (bottom row, panels d-f).

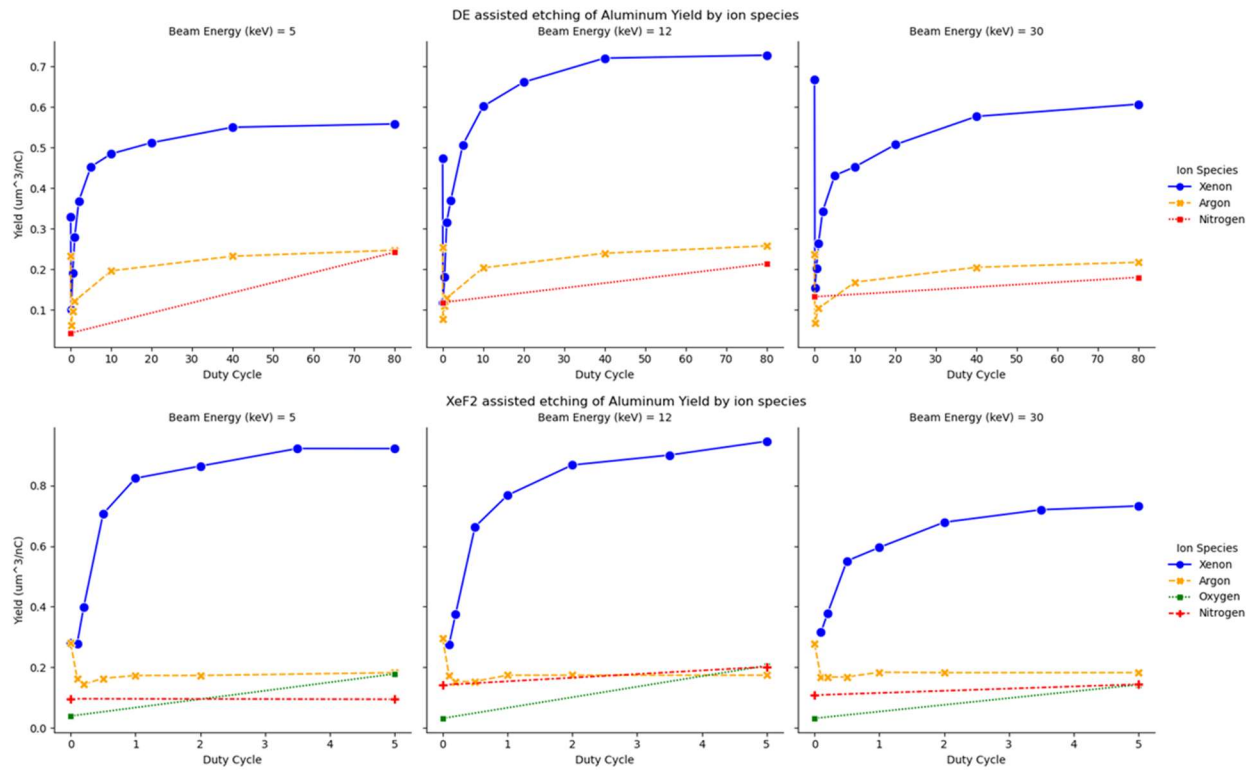


Figure 2. Etch yield vs duty cycle (gas flow rate) for DE- and XeF<sub>2</sub>-assisted aluminum etching using various ion species.